

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kazuaki EJIRI

Appln. No.:

10/749,599

Art Unit:

2818

Filed:

December 31, 2003

Examiner:

Calvin LEE

For:

CHEMICAL MECHANICAL POLISHING

Docket No.:

IGM-02001

METHOD, AND WASHING/RINSING METHOD ASSOCIATED THEREWITH

Certificate of Mailing

I hereby certify that the foregoing documents are being deposited with the United States Postal Service as first class mail, in an envelope addressed to : Mail Stop Amendment, Commissioner for Patents; P.O. Box 1450, Alexandria, VA 22313-1450 on this date of August 9, 2005.

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

PETITION FOR EXTENSION OF TIME

This is a request to extend the period for filing a response in the above-identified application for one month from July 27, 2005 to August 27, 2005. Enclosed is a check for \$120.00 to cover the extension fee.

Although we believe that we have submitted the correct amount to cover the requested extension of time, the Commissioner is authorized to credit any overpayment or charge any deficiencies to our Deposit Account No. 031721. Two originally-executed copies of this form are being submitted.

Should there be any questions after reviewing this paper, the Examiner is invited to contact the

undersigned at (617) 248-4038.

August 9, 2005

Date

Denald W. Muirhead Registration No. 33,978

Patent Group Choate, Hall & Stewart 2 International Place Boston, Massachusetts 02110

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